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TITLE: ELECTROSTATIC MAINTAINING DEVICE

PRELIMINARY AMENDMENT

Commissioner of Patents
and Trademarks
Washington, D.C. 20231

Sir:

In conjunction with the filing of the present application, and prior to an initial Official Action on this matter, please amend the above-identified application as follows:

IN THE SPECIFICATION

On page 1, please substitute the paragraph beginning with "Electrostatic" and ending with "holding device", as follows:

b1

Electrostatic Maintaining Device

On page 1, please substitute the paragraph beginning with "The invention" and ending with "vacuum, for example.", as follows:

BACKGROUND OF THE INVENTION

1. Field of the Invention

The present invention presented here involves an electrostatic maintaining device specifically designed to hold wafers of conductor or semiconductor materials such as silicon while they undergo micro-manufacturing or any other type of treatment such as plasma treatment in an enclosure under vacuum, for example.

On page 1, please substitute the paragraph beginning with "The different treatment" and ending with "automated mechanisms.", as follows: